IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

DRURY, THOMAS J.

Examiner Chang

Serial Number: 09/838,138

Art Unit 1771

Filing Date: April 20, 2001

For:

POLYVINYL ACETAL COMPOSITION

SKINLESS ROLLER BRUSH

The Honorable Commissioner of Patents and Trademarks Washington, D.C. 20231

Sir:

DECLARATION OF THOMAS J. DRURY

COMES NOW, Thomas J. Drury, who avers and swears that the following statements are true to the best of his belief and knowledge:

- 1. That I am the inventor of the Polyvinyl Acetal Composition Skinless Roller Brush as disclosed in U.S. Patent umber 09/838,138 and have been active in research and development in the polyvinyl acetal foam business for a number of years.
- 2. That I previously submitted a Declaration summarizing the text results obtained by Applied Materials Inc. on a roller brush product of the present invention which is identified as BPTOne 212XP material (3920-00307) and comparing the same with other rollers used in the marketplace including one developed by me.
 - 3. That a copy of this test report is attached hereto as Exhibit A.
- 4. That on information and belief, Applied Materials Inc. makes approximately sixty percent (60%) of the world's semi-conductor production equipment.
 - 5. That the inventive roller brushes of the present invention designated BPTOne were also

tested in the comparative testing by Motorola Inc. against Rippey brushes. A copy of this test is attached hereto as Exhibit B.

- 6. That Rippey brushes are believed to be those disclosed by Bahten Patent No. 6,076,662 (assigned to Rippey Corporation). Rippey Corporation had previously distributed the Kanebo brush (See the Tomita Patent Number 4,566,919).
- 7. That another independent commentary on the present inventive roller brush by a respected non-affiliated individual consultant is attached hereto as Exhibit C.
- 8. That the consultant commentator is Hal Bailey, a semi-conductor industry expert who heads several silicon valley think tanks including BASYS Group and Phrason Dynamics.
- 9. That the present invention has been calculated by Mr. Bailey to result in a savings on one semi-conductor chip processor of Three Hundred Twenty Thousand Dollars (\$320,000.00) per year.
- 10. That I am familiar with Ronald J. Cercone and Soloman Rosenblatt having worked with both parties for a number of years and am familiar with the products developed by both parties.
- 11. That roller brushes developed by Cercone and Rosenblatt are not known by me to have gained significant acceptance by the industry and are not believed to have significant, if any commercial usage in the silicon chip industry.

The undersigned declares that all facts and allegations contained in this declaration are true to the best of his knowledge; all statements made herein of his own knowledge are true and that all statements made on information an belief are believed to be true; and further, that these statements and the like so made are punishable by fine or imprisonment or both, under Section 1001 of Title 18 of the United States code and that such willful false statements may jeopardize the validity of the

application or document or any registration resulting therefrom.

Respectfully submitted,

Date: October 30, 2003

Thomas J. Drury

Summary

Objective:

To evaluate, and compare, defect performance of four different brushes, under the same environment.

Tool used:

- 300MM Mirra Messa.

Results:

BPTone 212XP material (3920-00307) had the best particle removal rate.

Experimental Details For Tool Qualification

Tools

- S3 300mm Mirra-Mesa
- Megasonics
- Brush 1
- Brush 2
- SRD
- Metrology
- KLA-Tencor
- Oxide BKM recipe

Methodology

- Cycle 100 dummy wafers through the system daily
- Testfire 4 oxide defect wafers
- Defect Qualification is < 30 adders (delta = post pre) at 0.13 μm
 - Cleaning Performance Metrics:
- Delta = precount postcount (typically used at customer site)
- Map-to-map defect analysis not available

Experimental Details for Brush Type Evaluation

Methodology

- Install Brushes and Run Brush Break-in twice
 - Cycle 25 dummy wafers through system
- Testfire 4 oxide defect wafers for qualification
- Defect Qualification is < 30 adders (delta = post pre) at 0.13 μm
 - Testfire 5+ oxide defect wafers for Using BKM 1.1
- Cleaning Performance Metrics:
- Delta = precount postcount (typically used at customer site)
- Map-to-map defect analysis not available

Evaluate Four Different Brushes for Brush Module 2

Brush types

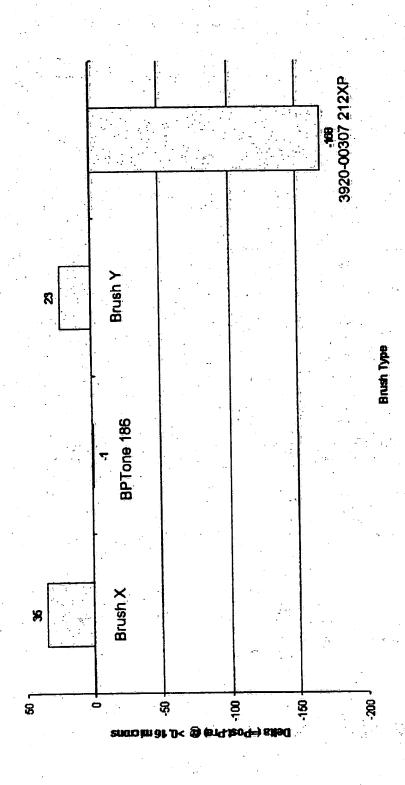
Brush X

Brush Y

BPT-1 Type 186

3920-00307, BPT-1 Type 212

Effect of Different Brush Types



Type 212 Brushes Has Best Defect Performance Applied Materials Confidential BPT-1

CMP PRODUCT BUSINESS GROUP

Final DI only cleaning test								
Wafer	pre-count @ >.16	pre-count @ >.2	post-count @ >.16	post-count @ >.2				
1	298	79	14	6				
2	241	112	9	2				
3	38	20	19	7				
4	43	14	14	5				
5	46	16	24	4				
6	41	15	24	5				
7	44	14	26	6				
8	52	20	24	6				
9	37	6	33	16				
10	39	13	22	7				
11	48	18	16	1 1				
12	61	16	18	8				
13	41	20	33	20				
14	59	17	23	10				
15	66	24	43	18				
	Average particles @ > .16 microns (pre) 76.93	Average particles @ > .20 microns (pre) 26.93	Average particles @ > .16 microns (post)	Average particles @ > .20 microns (post)				
•	Average particle rem	oval at > .16 microns	(54.13)	 8.07				
	Average particle rem	oval at > .20 microns	(18.87)					

Wafers 1 and 2 were the main reason for high average particle removal rate. The results of the removal rate average are quite impressive. The BPT One Brushes show better cleaning performance then any other brush I have used. The removal rates generally average from adding 2 particles to removing 3 particles at .2 microns. By removing wafers no. 1 and 2, the removal rate at .16 was -22.77 and at .20 microns -7.89 average. This data shows that the BPT One brushes clean twice as good then Rippey brushes and their equivalent. Of special note in this test, wafer no. 9 was the only wafer to add particles. This is due because originally the wafer showed a scratch across the wafer on the Tencor. It turned out to be a solid line of particles. During post reading, almost all the particles were removed and the wafer no longer had a scratch count. This is the type of issue I mentioned above about smaller particles causing loss of Die.

AREA

Data thrown out due to bad wafers

		Pre BPT area	Post BPT area	Delta BPT area	Pre b area	8 .7	Post b area	Delta t area		Pre c area	Post c area	Delta c area
	4	30			•	10	3		-7	. 9	9	Ü
•	1		<u></u>	-5		17	2	:	-15	14	, 9	-5
•	2	12		-15		6	2		-4	12	12	0
	3	16	-			7	4		-3	8	, 5	3
	4	14		-13		13	. 9	l	-10	11	7	-4
	5	. 3		-2	1		7	,	-7	13		-7
	8	10)	5 -4		14	,	,	-2	10		4
	7	10	1	· -9	:	44) S	-8	17	_	-9
	8	: 5	;	3 -2	•	17	-	· ·	0	17		-10
	g	3	3 () -3	}	7	•		U	2		ı -17
	10) 6	\$.	3 -3	3					_	•	-14
	11	9	3	4 -5	5		•			19	Ī	5
	12	19	10	3 -3	3		-				9 4	-5
	13			3 -4	, .					,	9	<u>.</u>
			, 1	- 3 -4	\$			•		1:	_	5 -7
•	14	•		5 -7	7	25		5	-20	4	1 12	2 -29
	15	5 1:	٠	•				•				
Totals:				-10	0		••		-76	i		-121

Total Defect

Totals:

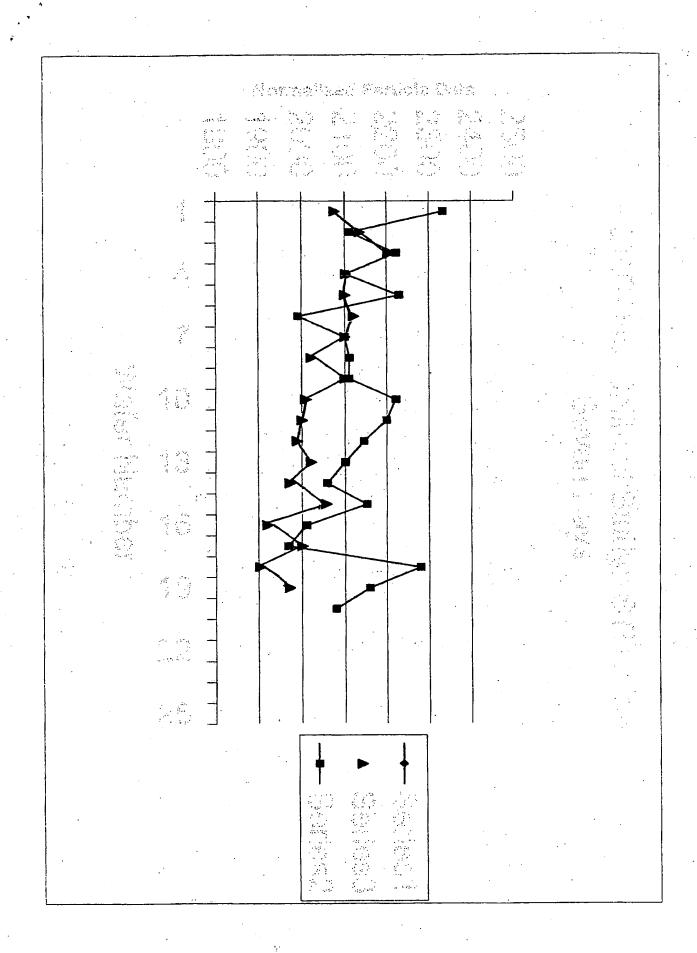
Data thrown out due to bad wafers

	n - 557	Deat BOT	Delta BPT		Post b	Delta b	Pre c	Post c	Deita c
			Tot. Def	Pre b Tot. Def	Tot. Def				
٠.	Tot. Def.		•	223	78	-145	151	140	-11
1	347	199		383	82 82	-301	355	131	-224
2	158	88			39	-39		193	14
3	117	69				-64			
4	186	110							
5	123	· 74			39				
6	160	98	-62						
7	242	. 72	-170	137					
8			-24	. 91	54	-37			
9				87	61	-26	300		
_			·				297		
10							407	82	
11		·					69	85	; 16
12							89	79	-10
13							59		45
14	93				. 70	45			
15	5 111	75	5 -36	3 115	5 70	, -4:	, 100		-
			-1439	2		-893	3	•	-1463

Scratch D fect

Data thrown ut du to bad wafers

		Pre BPT SCR.	Post BPT SCR	Delta BPT SCR	Pre b SCR	Post b					Delta c SCR
			-			0	1	1	6	5	1
	1	12	_	_	•	8	2	-6	8	3	-5
	2	5	/	-	2	6	1	-5	6	7	1
	3	3			4 .	5	2	-3	Ō	0	. 0
	4	4	1	_	5	5	2	-5	3	. 2	-1
*	5	5	5 5	5		0.	U.	-2	2	- n	-3
	6	7	2 0) 	2 .	3	1	_		3	-2
	7	3	3 2	2 -	1	2	2	0	. 5	3	4
	8		; 6	3	1	1	2	1	5	1	
,	⁻ 9	•	ı (} -	1	0	1	1	. 13	4	-8
	10	10)	5 -	5 .				5	U	-5
	11		1 1	1 -	3			•	. 12		-9
	12		7 2	2 -	5				. 0	1	1
	13			- 0	2 :	•			2	1	-1
	14		1	1 .	0				2	2	. 0
	15		2 (o -	2	0	0	0	5	. 2	-3
Totals	£ .			-2	9			-13	•		-41



Subi:

Golden Gate Bridge for President

Date:

Monday, October 27, 2003 6:34:47 PM

From:

hal@silcon.com

To: td41ho@aol.com

Today, Tom, I had the opportunity to help AVS prepare for the Showcase Program in Portland Oregon. My contribution was to create the scope of information for the keynote address opening the conference and exhibits. The committee had two current users of BPT one Brushes, and the comment requested was "cost of ownership" development.

Why, these two separate users replaced Rippey brushes every 6-8 weeks or less, and with BPT one, they replace twice per year. They invited me to provide a Poster Display of my "next cost of ownership savings" based on the results achieved with the BPT one brushes of 40% savings in water and chemicals coupled to the long-term life of the brushes. Net savings on one processor is \$320,000 per year including the cost of the brushes.

The Poster Board will feature all the technologies of Phrasor Dynamics:

1) Super Critical Vapor Phase FEOL reactive/removal processing

2) Thermadynamic Vapor Phase BEOL reactive/removal processing

3) Contact Reactive/Evacuation Post Processing in plating, coating and CMP

4) Electrohydrodynamic DRY-OUT

As part of the Poster Board, BASYS, on behalf of Phrasor Dynamics, has created one poster that reviews polyurethane, poly vinyl alcohol, poly vinyl ethylene, and hybrids including the Extenza formulations. Hydrofera is referenced for hybrid micropore PVA materials. The poster contains a chemical and performance compatability chart that importantly shows Hydrofera's reasons for +300,000 wafer processed by each set of your brushes. The facing poster board will have actual pictures and statistical results form +2 years of usage.

Smile, Tom, the message of performance worked! Only the message was never published or channeled to market! Maybe my courtesy of speaker's notes and poster board copy will help the cause! Try www.avs.org for time and place in Portland Oregon.

Celebrate!

Hal Bailey Chairman The Golden Gate Bridge for President Committee يروال والمراجب والمعادية